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Application
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Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 107703		APPLICATION NO. 09/687,333 New U.S. Patent Application	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANTS Kazuyoshi TAMURA, Makoto KAWAI and Keiichi GOTO			
				FILING DATE October 27, 2000		GROUP	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME		CLASS	SUB CLASS
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY		CLASS	SUB CLASS
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
		"Nitrogen effect on oxygen precipitation in Czochralski silicon", F. Shimura and R.S. Hockett, 1986 American Institute of Physics, Appl. Phys. Lett. 48 (3), 20 January 1986, pp. 224-226					
EXAMINER				DATE CONSIDERED 6/10/02			
Examiner:	Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.						